IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:)	
		Examiner: George R. Fourson, III
Kiyofumi SAKAGUCHI, et al.)	_
		Group Art Unit: 2823
Application No.: 09/161,774)	
		Confirmation No.: 8032
Filed: September 29, 1998)	
For: PROCESS FOR PRODUCTION OF)	September 8, 2006
SEMICONDUCTOR SUBSTRATE		

Mail Stop Amendment

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

SIXTH INFORMATION DISCLOSURE STATEMENT

Sir:

In compliance with the duty of disclosure under 37 C.F.R. § 1.56 and in accordance with the practice under 37 C.F.R. §§ 1.97 and 1.98, the Examiner's attention is directed to the documents listed on the enclosed Form PTO-1449. Copies of the listed documents, other than U.S. patent documents, are enclosed.

REMARKS

An English-language Abstract for JP-A 60-196955 was obtained from a commercial database and is also enclosed.

FORMAL MATTERS

No fee is believed due; however, any fee required in connection with this paper should be charged to Deposit Account No. 06-1205.

CONCLUSION

It is respectfully requested that the above information be considered by the Examiner and that a copy of the enclosed Form PTO-1449 be returned indicating that such information has been considered.

Applicant's undersigned attorney may be reached in our Washington, D.C. office by telephone at (202) 530-1010. All correspondence should continue to be directed to our address given below.

Respectfully submitted,

/Daniel S. Glueck/ Attorney for Applicant Daniel S. Glueck Registration No. 37,838

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FORM PTO 1448 (modified)	03500.010530.4 (35.C1650 C1/02)	APPLICATION NO. 09/161,774			
U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE LIST OF REFERENCES CITED BY APPLICANTIS)	APPLICANT Kiyofumi SAKAGUCHI, et al.				
(Use several sheets if necessary) Dated Submitted to USPTO: September 8, 2005	FILING DATE September 29, 1998	GROUP 2823			

SS FLING DATE IF APPROPRIATE
TRANSLATION YES/NO/ OR ABSTRACT
Abstract

T. Yasumatsu, et al., "Ultrathin Si Films Grown Epitaxially on Porous Silicon", Applied Surface Science, Vols. 48 & 49, pp. 414-418 (1991)

Handbook of Thin Film Technology, 5-17 to 5-25 (Eds., L. I. Maissel and R. Glang 1970)

Robert F. Pierret, Semiconductor Device Fundamentals, pp. 347-368

EXAMINER DATE CONSIDERED

"EXAMINER: Initial if reference considered, whether or not offation is in conformance with IMPEP 609, Draw line through obtation if not in conformance and not considered. Include copy of this form with next communication to applicant.

Sheet _1_ of _2_

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FORM PTO 1448 (modified) U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEDAMEN OFFICE LIST OF REFERENCES CITED BY APPLICANT(S) (Use several sheets if necessary) Date Submitted to USPTO: Suptember 8, 2008		ATTY DOCKET NO. 03500.010530.4 (35.C10530 C1/D2)	APPLICA	APPLICATION NO. 09/161,774					
		APPLICANT Kiyofumi SAKAGUCHI, et al.							
		FILING DATE September 29, 1998	GROUP 2823						
		U	S. PATENT DOCUMENTS						
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		FORE	EIGN PATENT DOCUMENTS						
	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES/NO/ OR ABSTRACT			
OTHER DOCUMENT(S) (Including Author, Title, Date, Perlinent Pages, Ello.)									
	S.M. Sze, Physics o	f Semiconde	uctor Devices, pp. 63-128, 847-84	9, 2 nd E	dition (1981)			
W. Kern & V. Ban, <u>Thin Film Processes</u> , Chemical Vapor Deposition of Inorganic Thin Films, pp. 257-331 (1978)									
W. Luft & Y. Tsuo, <u>Hydrogenated Amorphous Silicon Alloy Deposition Processes</u> , pp. 125-144 (1993)									
	R. Pierret, Modular Series on Solid State Devices, Vol. 4, pp. 59-80 (1983)								
EXAMNER			DATE CONSIDERED						
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